

PRODUCT TECHNICAL BRIEF

Oxford Instruments C-Nano+ EBSD System

Oxford Instruments C-Nano+ EBSD System - LeakLab solutions for leak testing, vacuum systems and test equipment.

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Technical Data

PARAMETER	PUBLISHED VALUE / INFORMATION
Maximum guaranteed indexing speed	600 patterns/s at 3 nA
Pattern resolution at maximum speed	311 × 256 pixels
Full pattern resolution	1244 × 1024 pixels
Angular precision stated by the manufacturer	Better than 0.05°
Detector interface	Lens-free fibre optics with bellows SEM interface
Protection	Proximity sensor for collision avoidance
Options	Five integrated forescatter detectors and EDS integration

Technical and Project Information

CMOS electron backscatter diffraction system for crystallographic orientation, phase and strain analysis in compatible SEMs. The current C-Nano+ specification lists more than 600 indexed patterns per second and full 1244 × 1024-pixel patterns.

C-Nano+ acquires electron backscatter diffraction patterns for orientation mapping, phase discrimination, grain-boundary analysis and strain-sensitive studies. It can be integrated with Oxford Instruments EDS through the AZtec platform.

The former page referred to an earlier C-Nano at 400 frames/s. This revision uses the current C-Nano+ public specification. Confirm SEM chamber geometry, specimen tilt and working distance, beam-current capability, stage repeatability, software modules, phase database and installation clearance.

- Helium Reference Leaks
- Scanning Electron Microscopes
- Leak-Detector Accessories

WORLDWIDE PROJECT CONTACT

Send the test object or system, operating conditions, target sensitivity or pressure range, applicable standard, destination country, quantity and schedule. LeakLab will review the project scope.

mail@leaklab.org

Regarding: Oxford Instruments C-Nano+ EBSD System

Specifications, standards, verification scope, availability and commercial terms must be confirmed for the exact configuration and destination jurisdiction before order or project acceptance.